



Gemma Tinti for the Swiss Light Source Detector Group

EIGER: high frame rate pixel detector for synchrotron and electron microscopy applications

PIXEL 2018



SLS-detector group detectors

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	MYTHEN II&III	EIGER	GOTTHARD I & II	JUNGFRAU	MÖNCH	AGIPD
1D/2D	Strip	Pixel	Strip	Pixel	Pixel	Pixel
Working Mechanism	Photon Counting	Photon Counting	Charge Integrating	Charge Integrating	Charge Integrating	Charge Integrating
Strip/Pixel size [µm]	50	75×75	25/50	75×75	25×25	200×200

Poster X.Shi

R. Dinapoli on Thursday

PSI EIGER: high frame rate pixel detector:

- 1) synchrotron
- 2) electron microscopy



EIGER: ASIC characteristics

Single photon counter

Monochromatic >	⟨-ra <u>ys</u> ₀	
⊏J ※	Adj. Gain	Global Threshold V _{cmp}
L ∀		
	1	counter

Single photon counting detector

Pixel size	75 x 75 um ²
Pixel matrix	256 x 256
Counter	4/8/12 bit
Frame rate	23/12/8 kHz
Data rate	6 Gb/s
Threshold adj. bits	6
Threshold dispersion (after trimming)	<10 e⁻
Noise	100-200* e⁻ RMS
Rate capabilities (10% deviation)*	500 k counts/pixel/s \rightarrow 90 Mphotons/mm ² /s
Dead time	4 us (with buffering)

^{*}Depending on gain setting

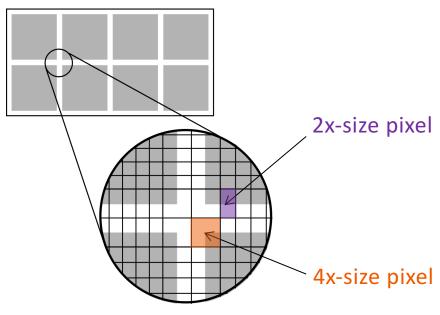


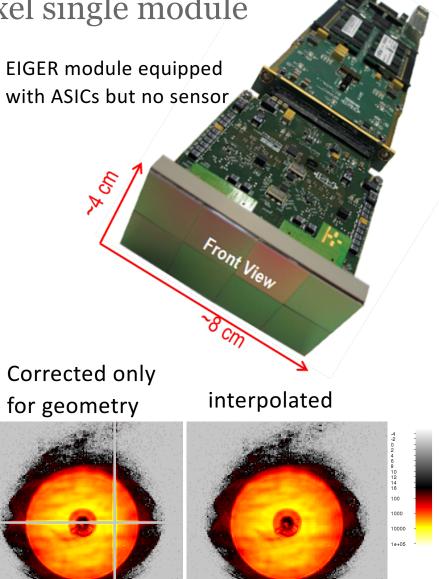


EIGER: 500k pixel single module

- 2x4 chips
- Single 4x8 cm² silicon sensor
- Sensor thickness 320 μm

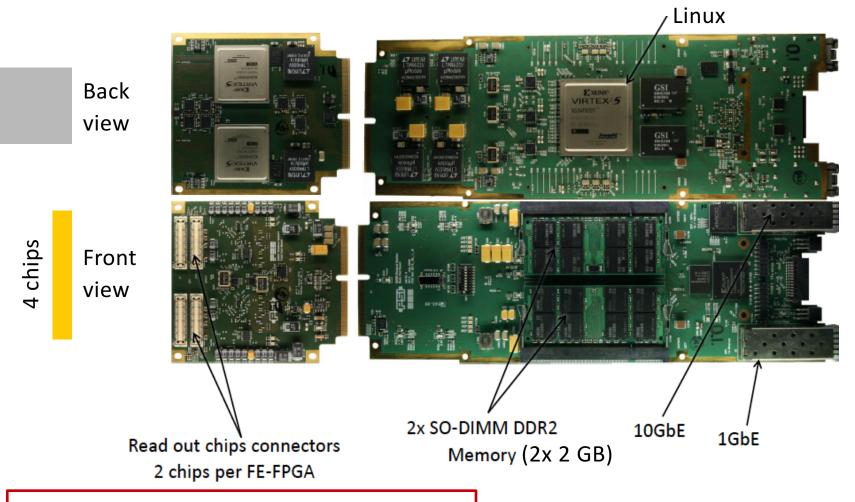
No dead area in a single module!







EIGER: Readout System



- Image summation 12 → 32 bit
- Data buffering
 - → preserve high frame rate capability
- Possibility to apply corrections

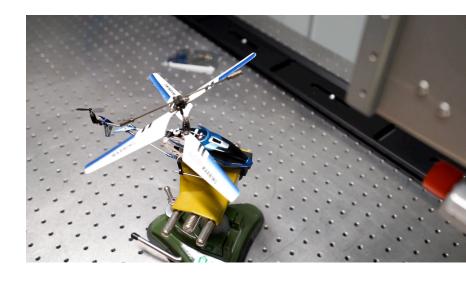
Half module is basic readout unit.

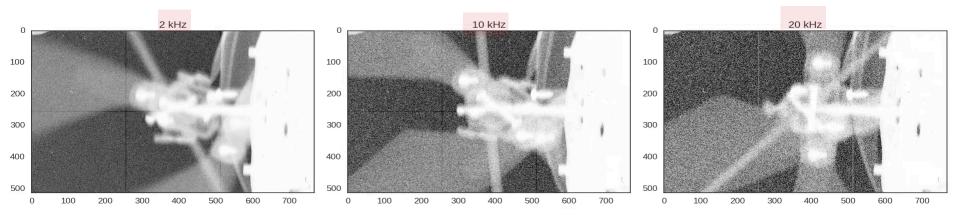
A module is readout as 2 half modules (20 Gb/s)



Very high frame rate detector

Dynamic range (bit)	Buffered max frame rate (kHz)	Data buffered (# images)
4	22	30000
8	11	15000
12	6	7600
32	2	Online sum





Displayed normalized to 30 imgs/s

High frame rate at synchrotrons: 20 kHz Time evolution: K. Woll's group (KIT) As-deposited 1200 Temperature (°C) Powder sample with ultra fast heating 400 MS + microXAS beamlines @ SLS 50 60 Time (ms) $g_2(q,t) - 1$ **ID02 @ESRF** colloids Eiger 500k 66 - 95 m XPCS technique (Advective) detector & 62 m Eiger beamstop sample 0.08 guard slit S5 $g_2(q,t) - 1$ secondary slit S4 0.06 secondary slit S3 double mirror 0.005 0.010

T. Zinn et al.,

J. Synchrotron Rad. (2018). 25

toroidal & planar

monochromator

27.5 m

primary slit P1

26

(c)

0.0035 (nm⁻¹)

0.0045 (nm⁻¹)

0.0060 (nm⁻¹) 0.0075 (nm⁻¹) 0.0090 (nm⁻¹)

0.0105 (nm⁻¹)

q [nm⁻¹]

10-1

10-2

t[s]

Pilatus 300k

(Advective)

 10^{-3}

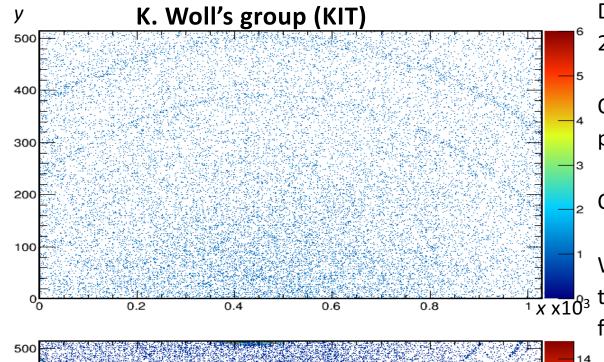
0.00

10-4



Detector occupancy

POWDER DIFFRACTION



Diffraction pattern recorded at 20kHz (45 μs exposure + 5 μs)

Occupancy here defined as: # pixels with hits/# pixels

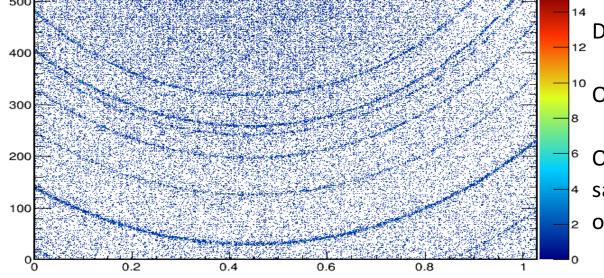
Occupancy~ 4%

With optimization of the sample $^{1}x \times 10^{3}$ thickness it is expected to gain a factor 5-10 in hits

Diffraction recorded at 20kHz

Occupancy ~11%

Obtained from calibration
 sample: more representative
 occupancy





Online compression studies

Dynamic range (bit)	Continuous	Buffered max	Data
	frame rate @10	frame rate	buffered
	Gb (kHz)	(kHz)	(images)
4	10.2	22	30000

2x10 GbE links/module are bottle neck

We need compression factor x2.2 to go continuous

- HIT BASED READOUT: only if OCCUPANCY < 14% module
 - Send address and value only of pixel with hits
 - Typically we have a few % occupancy
- ZERO COMPRESSION: instead of writing all the half-bytes that are zeros, write a
 flag and #half-bytes that are zero:
 - 0000 0000 0000 0000 0001 -> 1111 0100 0001
 - Real 1111-> 1110, Real 1110-> 1111 0001

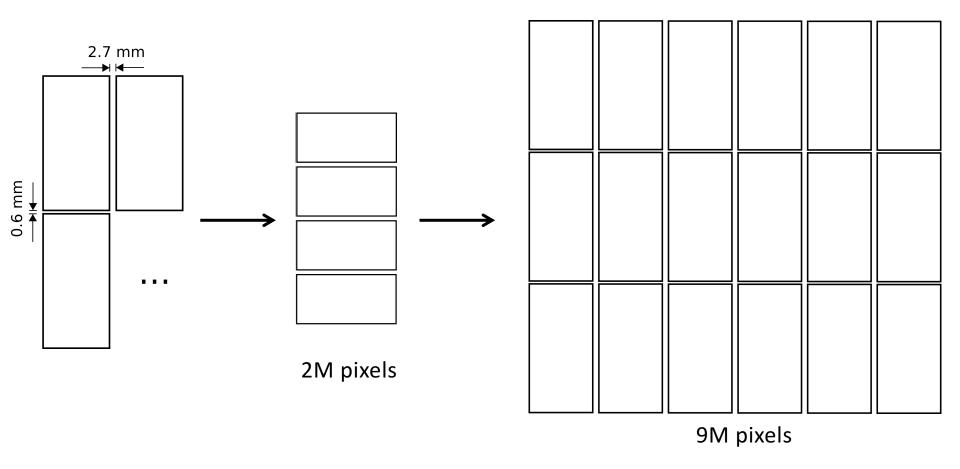
This study refers only to powder diffraction data

Dataset	Hit based readout	Zero compression	Reference GZIP, level 2 offline
Low occupancy	3.2	5.9	11.5 in 8 bit
High occupancy	1.4	3.4	6.9 in 8 bit



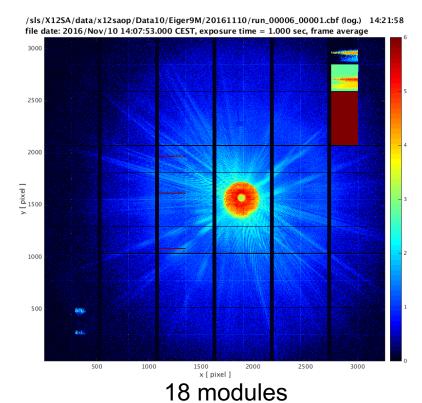
EIGER: Larger systems

- Modules can be tiled to large area detectors
- Due to the parallel design there is no penalty in performance when moving from a single module to multi module systems

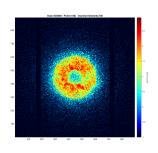




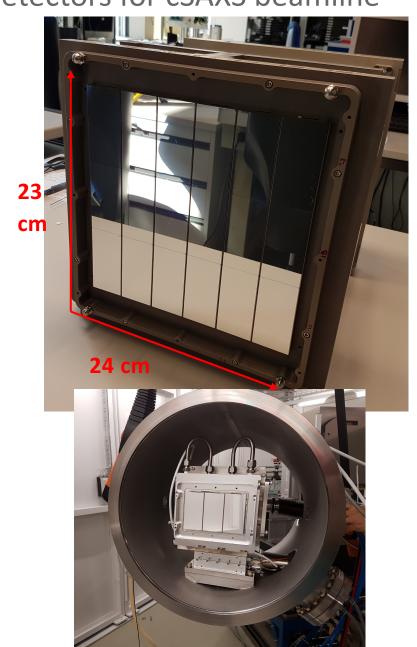
PSI Eiger 1.5 and 9M detectors for cSAXS beamline

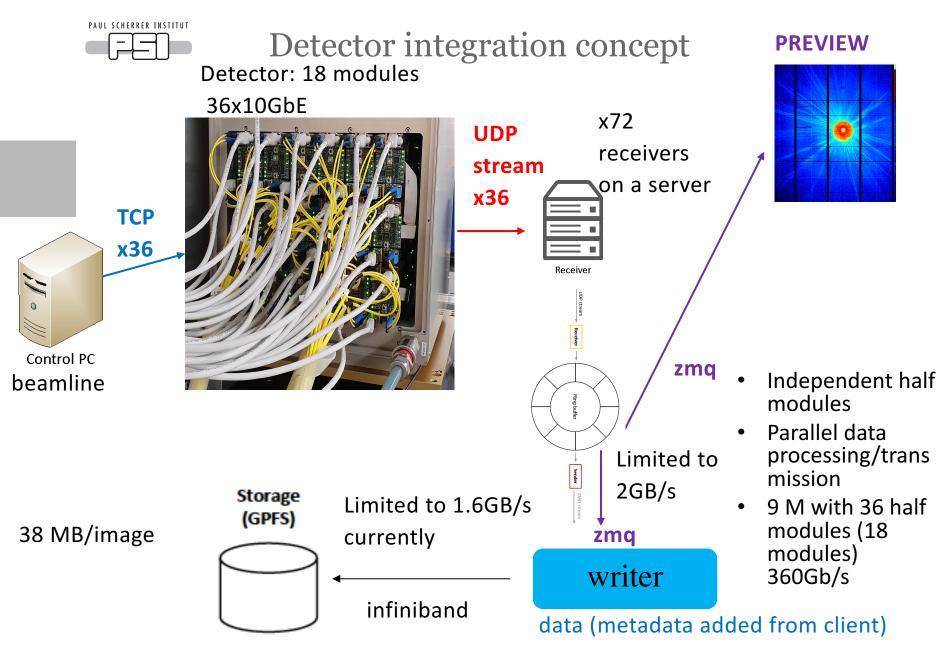


- 1.5 M in user operation since April 2018
- 9M foreseen user operation Feb 2019



3 modules





Phase I: User operation at minimum 25 Hz for 32-bit starting from Feb 2019 Expected: 42 Hz, 1.6GB/s. The detector can send out up to 45 GB/s



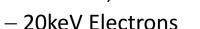
EIGER: high frame rate pixel detector:

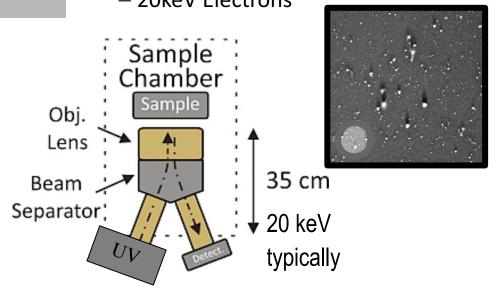
- 1) synchrotron
- 2) electron microscopy



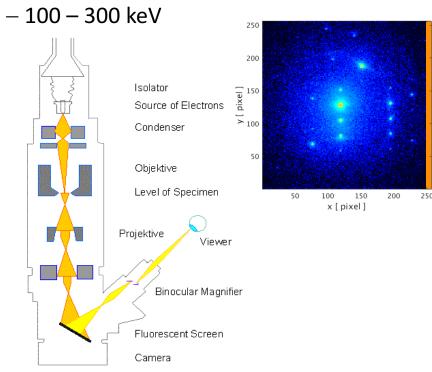
EIGER in electron microscopy

- PEEM Photo Emission Electron
 Microscopy Imaging
 - ELMITEC, SIM Beamline SLS





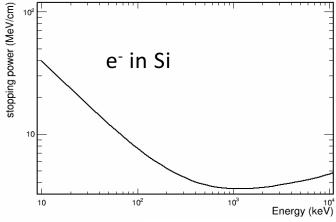
- TEM Transmission electron microscopy -Electron Diffraction/(Imaging)
 - Prof. Jan Pieter Abrahams C-CINA/PSI

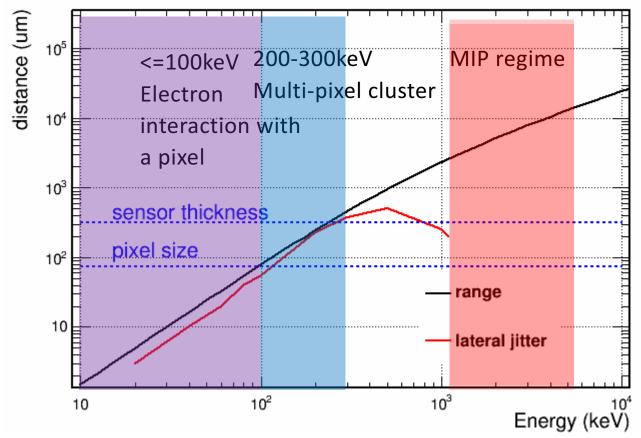


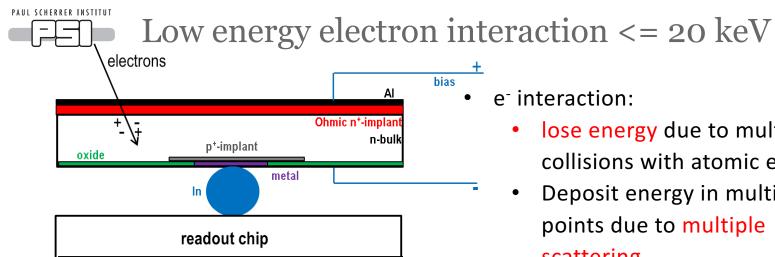
- Quad:
- active area 4x4 cm²
- In vacuum
- For energies <=100 keV, hybrid pixels are an "ideal detector"
- At higher energies, EIGER is appealing thanks to frame rate: scanning/rotation techniques, imaging single electrons, reducing sample drift



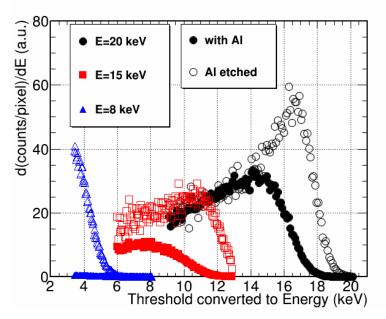
EIGER as an electron detector







Completely rad hard for 8-20 keV e⁻¹



e interaction:

- lose energy due to multiple collisions with atomic electrons
- Deposit energy in multiple points due to multiple scattering
- Al layer can be etched away
- e-lose part of their energy in Si backplane

Cham dand	Material crossed	20 keV e ⁻	10 keV e ⁻
Standard entrance	Al 1 μm	2.6 keV	5.0 keV
window	Si 1.5 μm	3.0 keV	4.0 keV

Tinti et al, J. Synchrotron Rad 24 (2017)



FBK thin entrance window sensors

Sensor produced by FBK Trento:

Al has also been etched away

- 1. As implant tested (~200 nm)
- 2. As implant low energy still to be tested

Tested with a TEM from J.P. Abrahams's group

	;	×10 ⁶								2	0 k	e\	V									
a.u.)		_															:		:		i	
d(counts/pixel)/dE (a.u.)	120	_ _									Λ					_	new s	enso	r. Ale	tched		
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										tl	nre	sł	ol	d c	on	vert	ed	to e	enei	rgy (eV)	

Material crossed	20 keV e ⁻	10 keV e ⁻
Si 500 nm	1.2 keV	2.0 keV
Si 200 nm	0.5 keV	0.9 keV

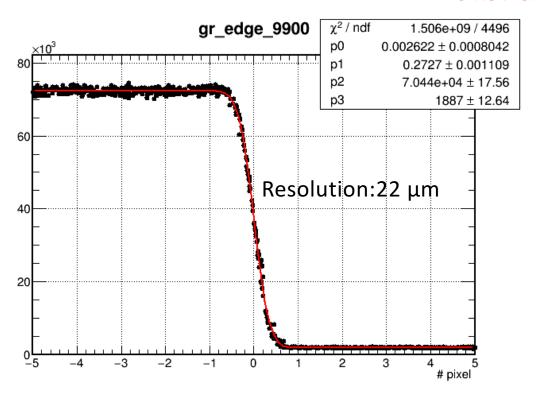
 $19.5 \text{keV} \pm 0.9 \text{ keV RMS}$

0.5keV lost in entrance window



Spatial resolution with low energy electrons

20 keV electrons



edge

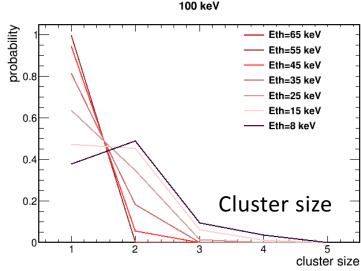
- When setting the threshold to half of the electron energy, we have single pixel resolution
- Fitting with a ErrFunction: resolution is 22 μ m, compatible with 75 μ m/sqrt(12)

Tinti et al, IUCrJ 5(2) (2018)

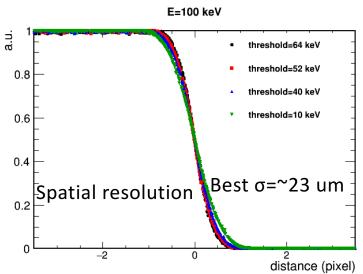


edge

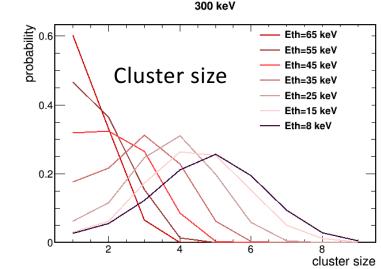
100-300 keV electrons



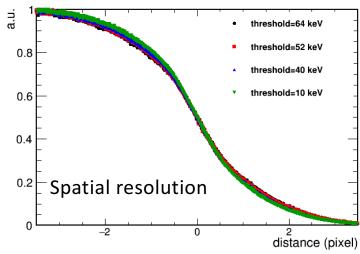
100 keV: Setting the threshold>50%, we recover single pixel resolution



100keV: Good for imaging and diffraction



The size of interaction is large: high threshold records higher energy hit but not entrance hit E=300 keV

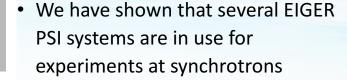


200-300keV: Good for diffraction

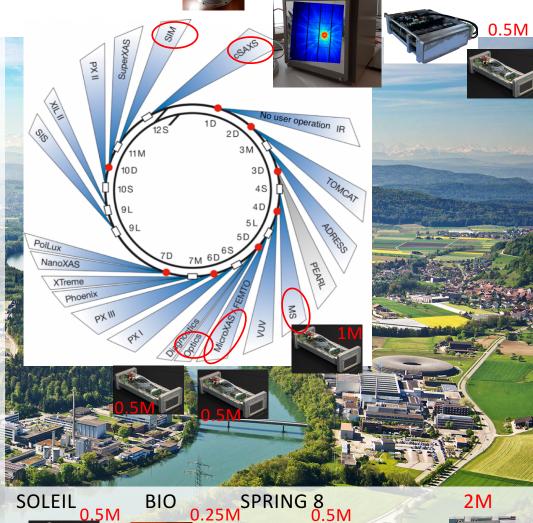


Conclusions

9M OMNY 1.5M



- The high frame rate make PSI EIGER unique: time resolved experiments are possible
- EIGER works well for low energy electrons (<=100keV) both for PEEM and TEM applications
- The fast frame rate capability makes EIGER interesting also for TEM applications at 200-300 keV
- We are working to reach even higher frame rates selecting a subsection of the chip or to have compression on board to reach continuous fast frame rate operation



0.25M

ESRF 2x0.5N



Acknowledgements



Back: (Marie Ruat,) Bernd Schmitt, Sophie Redford, Aldo Mozzanica, Erik Fröjdh.

Middle: Jiaguo Zhang, Carlos Lopez, Marie Andrä, Rebecca Barten, Martin Brückner, Christian Ruder,

Dominic Greiffenberg, Seraphin Vetter.

Front: Xintian Shi, **Dhanya Thattil**, Gemma Tinti, Anna Bergamaschi, (Marco Ramilli,) **Roberto Dinapoli**, Davide Mezza.

Not in picture: Sabina Chiriotti Alvarez



1MeV electrons

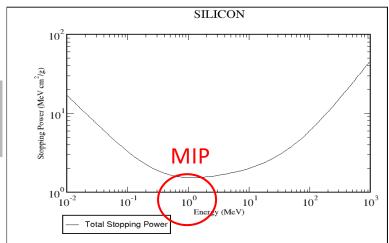
hits are recorded

spatial resolution

a bit worse than

We expect a

single pixel



- We expect the peak of the Laundau to be around 110 keV: 55 keV threshold
- Calibrated the detector threshold up to 110keV

8.399 / 5 3914 ± 37.14

 -0.06547 ± 0.002106 2.744e-07 ± 2.35 e-08

Eth=80 keV

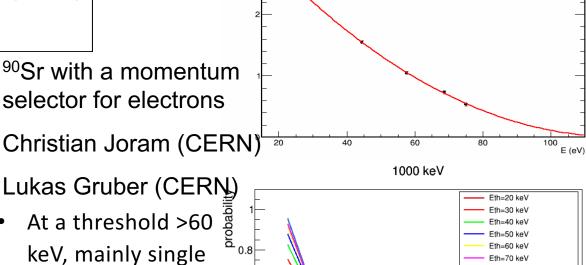
Eth=90 keV

Eth=100 keV

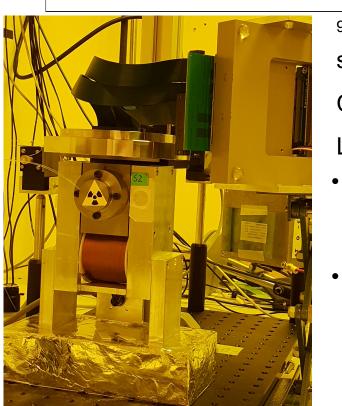
4.5

cluster size

3.5



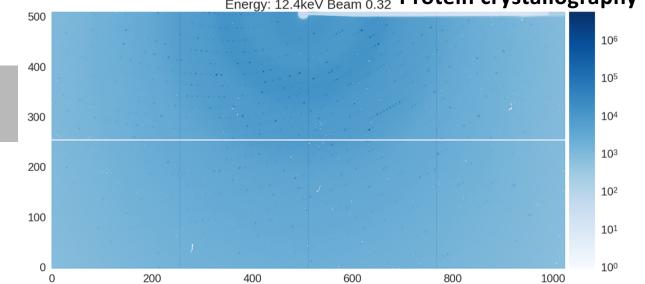
0.6





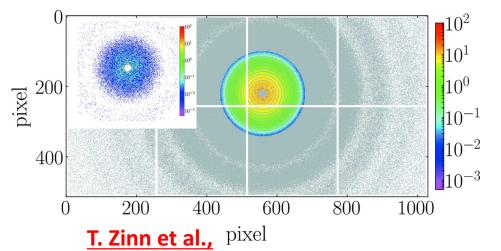
Experiments at synchrotrons





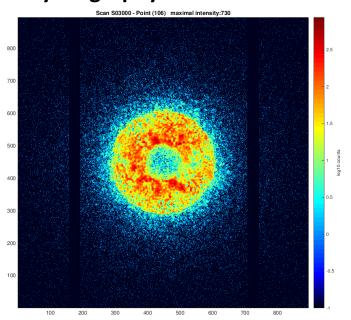
ALL compression findings for powder diffraction does not automatically apply to all experiments

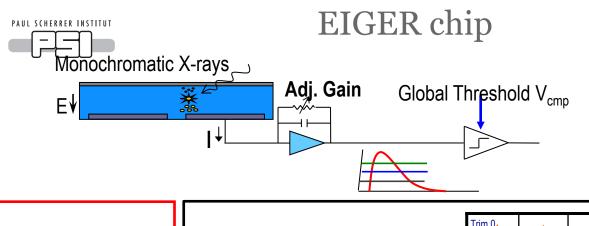
XPCS average and single **ESRF ID02** beamline



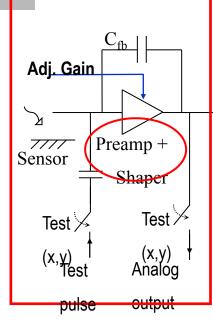
J. Synchrotron Rad. (2018). 25

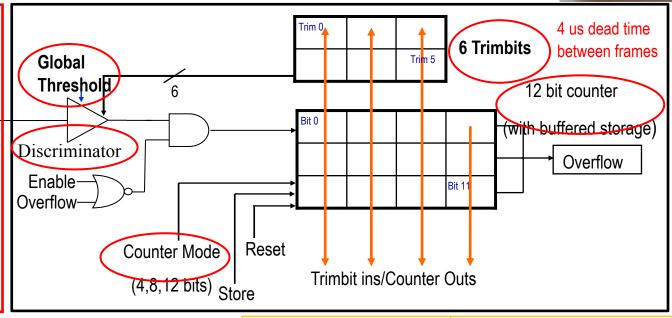
Ptychography cSAXS beamline







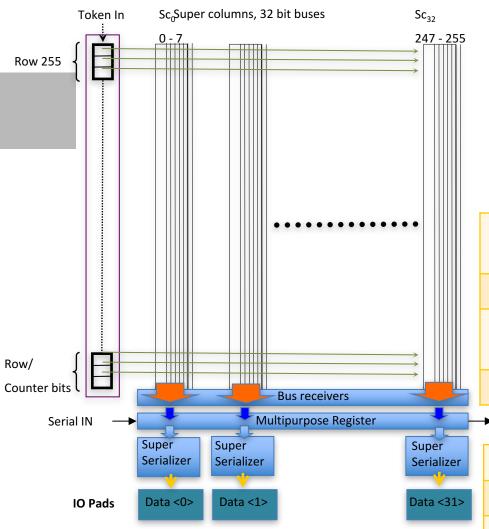


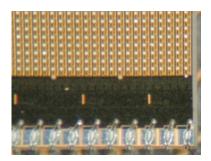


<u> </u>		Threshold dispersion	<10 e ⁻			
Pixel size	75 x 75 um ²	(after trimming)				
Pixel matrix	256 x 256	Noise	100-200 [*] e⁻ RMS			
Frame rate	23/12/8 kHz	Rate capabilities (10% deviation)*	500 k counts/pixel/s \rightarrow 90 Mphotons/mm ² /s			
Data rate	6 Gb/s	Dead time	4 us (with buffering)			

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Very high frame rate





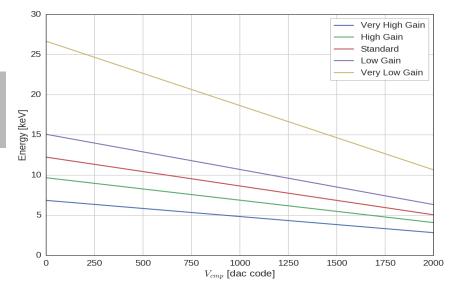
Threshold dispersion (after trimming)	<10 e ⁻
Noise	100-200* e- RMS
Rate capabilities (10% deviation)*	500 k counts/pixel/s \rightarrow 90 Mphotons/mm ² /s
Dead time	4 us (with buffering)

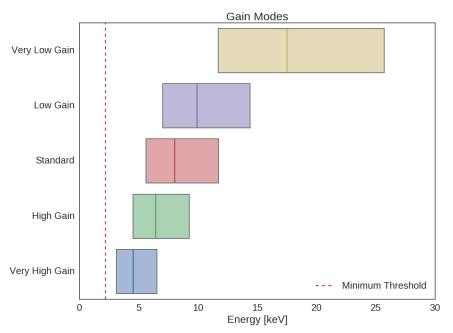
→ Serial OUT

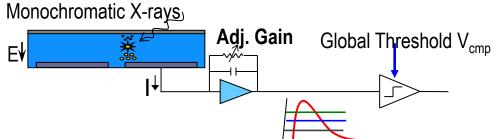
Pixel size	75 x 75 um ²
Pixel matrix	256 x 256
Frame rate	23/12/8 kHz
Data rate	6 Gb/s



Threshold calibration





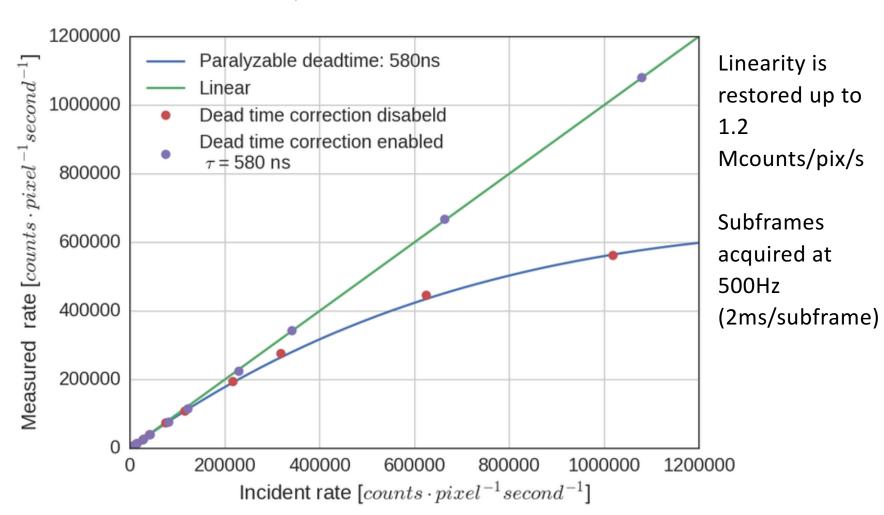


- Each **preamplifier gain** covers a different range of photon energies
- The threshold setting needs to be calibrated into photon energy
- Threshold is calibrated to be uniform in the detector and its dispersion is negligible (down to 10 e⁻) in comparison to noise
- The noise at high gain is < 100 e⁻
- Threshold can be set at > 2 keV (depending on the readout settings)



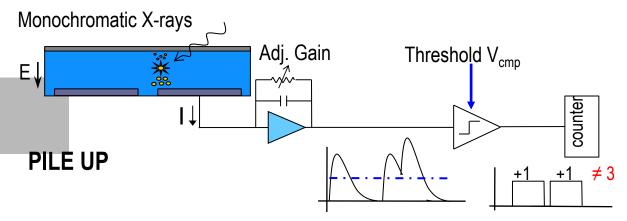
Online rate correction

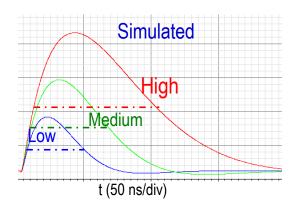
Single subframes recorded up to 2kHz frame rate can be corrected online, before summation

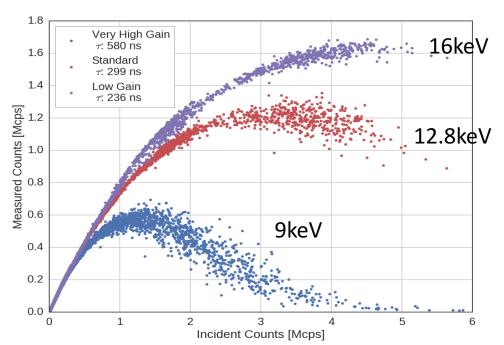


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Rate correction as a function of energy







For the same energy, lower gain improves the rate capabilities

Paralizable counter model:

$$N_{det} = N_{inc} \cdot e^{-N_{inc} \cdot \tau}$$

Linerity at 90%:

200 - 600

kcounts/pixel/s

Rate capability depend on the energy!



Rate corrections in 8 bit mode

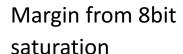
$$N_{det} = N_{inc} \cdot e^{-N_{inc} \cdot \tau}$$

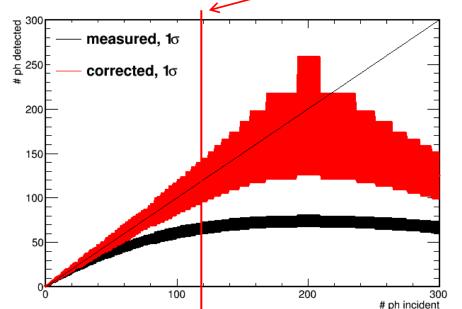
If $\Phi=1.5 \text{ MHz/pix}$, t=80 us, $N_{inc}=120$

Maximum flux

Chosen for linearity







Errors on corrected value 20%:

- Statistical uncertainty in N_d: $\sigma = 20\%$
- Pixel to pixel differences in tau: $\sigma = 2 - 15\%$
- τ =400 ns
- Rate corrections can be applied to 8bit data as N_{inc} does not exceed $N_{det} < N_{inc}$ 8bit depth (254)
- Rate correction, if wanted in firmware, needs to be implemented for 8bit data
- If more than 1 image taken in same condition → better to sum before and correct with higher statistics



Charge sharing

